MPS-201G

Value Added Medical Pressure Sensor



Disposable Blood Transducer Male / Male Luer (AAMI Standard)

The MPS-201G pressure sensor is specifically designed to meet the requirements as described in the Association for the Advancement of Medical Instrument (AAMI) specification for Invasive Blood Pressure Transducers.

The sensor consists of a pressure sensing element mounted on a ceramic substrate. Thick-film resistors on the ceramic substrate are laser-trimmed for calibration. A plastic cap is attached to the ceramic substrate to provide protection for the sensor, and to aid in assembly. An opaque dielectric gel is placed over the sensor for electrical and fluid isolation.

Medical grade materials are chosen to ensure compatibility with all medical tests and packaging is designed for automated assembly.

FEATURES

- Low cost
- Top Side Pressure Entry
- Fully Tested and Calibrated
- Dielectric Gel Barrier
- Biomedically Approved Materials

THE MAIN FIELD OF APPLICATIONS

- ✓ Disposable Blood Pressure Monitor
- ✓ Kidney Dialysis Machine
- ✓ Medical Instrumentation
- Infusion Pumps

MEMSENZTM I Transduction Principle Capacitive Processing Technology Bulk/Deep RIE Actuation Mechanism Force (External) Signal Condition Two chips/Single chip MEMSENZ[™] II Transduction Principle Piezoresistive Processing Technology Bulk/Deep Wet Etch Actuation Mechanism Pressure (External) Signal Condition Two chips/Single chip

MEMSENZ[™] III Transduction Principle Resistive Processing Technology Surface Actuation Mechanism Thermal Signal Condition Two chips MEMSENZ[™] IV Transduction Principle Capacitive Processing Technology Bulk Actuation Mechanism Sound Signal Condition Two chips



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Technical Data

Suitable for ETO sterilization.

Maximum ratings

Specification	Min.	Тур.	Max.	Unit
Operating Temperature	15	-	+45	S
Storage Temperature	-30	-	70	°C
Over Pressure (note 1)	125	-	-	psi
Supply Voltage	1	6	10	V

Data

Temperature=22±2℃, Relative humidity=45±5%

Specification	Min.	Тур.	Max.	Unit
Operating pressure range	-30	-	300	mmHg
Zero pressure offset voltage (note 1)	-25	0	25	mmHg
Sensitivity	4.95	5	5.05	μV/V/mmHg
Input impedance (note 1)	1800	-	3200	Ω
Output impedance Cal factor (150k Ω @ 0mmHg) Non-linearity (note 2)	285	300	315	Ω
	97.5	100	102.5	mmHg
	0	0.5	1	% span max
Output symmetry	-5	0	5	%
Warm up time	-	5	-	S
Drift time over 4 hrs	-	-	1	mmHg
Temperature coefficient of offset, TCO	-	-	0.1	%/C
Temperature coefficient of sensitivity, TCS	-	-	0.3	mmHg/C
Light sensitivity	-	-	1	mmHg
Defibrillator withstand (360 J/ 5 mins)	5	-	-	-

<u>Notes</u>

- 1: This parameter may vary from product to product
- 2: Follows AAMI BP22 accuracy standards
- 3: Based on the standard for the targeted medical device

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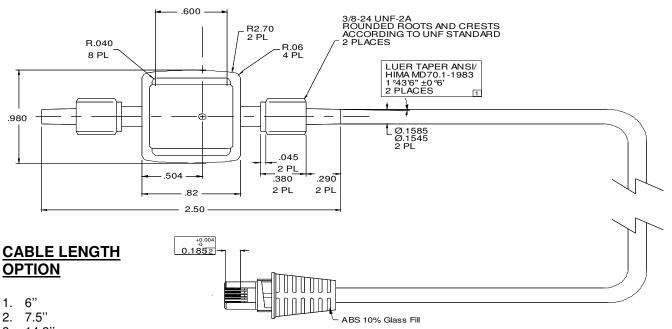
MEMSENZ[™] III Transduction Principle Resistive Processing Technology Surface Actuation Mechanism Thermal Signal Condition Two chips

MEMSENZ[™] IV Transduction Principle Capacitive Processing Technology Bulk Actuation Mechanism Sound Signal Condition Two chips

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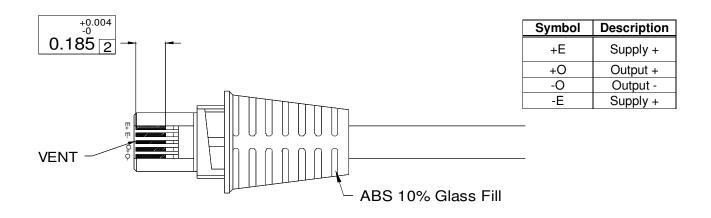
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MECHANICAL DIMENSIONS



- 3. 14.2"
- 4. 42'

ELECTRICAL & PIN LAYOUT



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MEMSENZ[™] III Transduction Principle Resistive Processing Technology Surface Actuation Mechanism Thermal Signal Condition Two chips

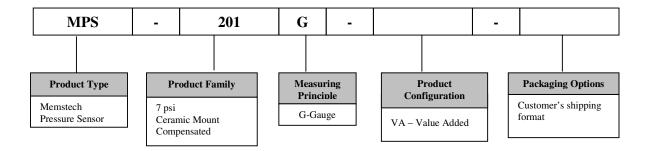
MEMSENZ[™] IV Transduction Principle Capacitive Processing Technology Bulk Actuation Mechanism Sound Signal Condition Two chips

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MPS-201G

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HOW TO SPECIFY PART NUMBER



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WARRANTY:

Subject to the conditions set out below in this Clause, MemsTech and its subsidiaries warrants its products against defects in material and workmanship for a period of 12 months from the date of shipment. Products that are not subjected to misuse will be repaired or replaced. MemsTech and its subsidiaries reserves the right to make changes to any product herein without further notice. MemsTech and its subsidiaries makes no warranty, representation or guarantee regarding the suitability of its products for any application, nor does MemsTech and its subsidiaries assume liability arising out of the application or use of any product or circuit and specifically disclaims all liability without limitation consequential or incidental damages. The foregoing warranties are exclusive and in lieu of all other warrante, whether written, oral, implied or statutory. NO IMPLIED STATUTORY WARRANTY OF MERCHANTABILITY OR FITNESS FOR A PATICULAR PURPOSE SHALL APPLY. This warranty does not extend to parts, materials or equipment not manufactured by MemsTech and its subsidiaries and this warranty is further subject to the conditions that MemsTech and its subsidiaries shall be under no liability whatsoever in respect of any defect in the products arising from any drawing design or specifications (whether oral or in writing), misuse or alteration or repair of the products without MemsTech and its subsidiaries' approval. The provisions herein are governed by the laws of Malaysia.

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